

## **INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Application Number	10/797,046
Filing Date	March 11, 2004
First Named Inventor	Jung-hyun Lee et al.
Examiner Name	SARA W CRANE
Attorney Docket No.	1030681-000634

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**U.S. PATENT DOCUMENTS**

## FOREIGN PATENT DOCUMENTS

Post Office that issued the document for the two-letter code.

## NON-PATENT LITERATURE DOCUMENTS

Examiner initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
	Sheh, Oier et al., <i>Thin film atomic layer deposition equipment for semiconductor processing</i> , Thin Solid Films 402 (2002) 248-261
	Copy of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929
	English Translation of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929

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